

Specifications

Standard Reference Instrument Series 6006

Precision Micro-machined Apertures

Description: Precision micro-machined apertures are fabricated from silicon on insulator (SOI) wafers. Lithographic processing allows great flexibility in the aperture design, enabling precise placement of apertures, through holes, and chip outlines. Optionally, metal can be deposited for low emissivity. Multiwall vertically-aligned carbon nanotubes can be grown for high emissivity on chips containing through holes but no precision apertures.

Design, fabrication, and technical measurements leading to the production of this SRI were performed by N. Tomlin, NIST Applied Physics Division.

Support aspects involved in the issuance of this SRI were coordinated through the NIST Office of Reference Materials.

Specifications: Aperture design is subject to review to ensure it is possible to fabricate. See attached figure for sample aperture design. The side with the precision aperture is referred to as the front. The following design guidelines are recommended:

- Precision aperture:
 - Aperture thickness:
 - Options 6006a & 6006b: 8-12 μm (typically 10.5-11 μm , but may not be able to specify, depends on SOI wafer availability)
 - Options 6006e & 6006f: 200-1000 nm (typically \sim 500 nm, but may not be able to specify, depends on design)
 - “Pullback” from edge behind aperture can only be a maximum of 2-3 μm (see example drawing below)
 - Aperture width: 10 μm to 5000 μm
 - Shape: rectangular, circular, more complicated shapes possible pending review
- Chip:
 - Length of longest line drawn between any 2 outline points: 63.5 mm (must fit on 76.2 mm diameter wafer)
 - Thickness: 300-600 μm (may not be able to specify, depends on SOI wafer availability)
 - Outline minimum feature size: \geq 200 μm
- Backside channel width: 200 μm to 6000 μm (must be wider than aperture width)
- Through hole minimum feature size: \geq 200 μm
- Dimensions specified in metric units (millimeter or micrometer preferred)
- Option 6006b & 6006f: metal coating on aperture/front side:
 - Electron beam deposition
 - Metal coverage: “blanket” front side, no patterning possible

- Metals available: Ag, Al, Au, Cu, PdAu, Pd, Pt, Ti, V (as of writing, depends on metal availability when purchased)
- Metal thickness: 50 nm to 500 nm
- Option 6006g: vertically-aligned carbon nanotubes (VACNT) on one side:
 - Incompatible with precision aperture, compatible with through holes only
 - Si thickness: 300-500 μm (may not be able to specify, depends on Si wafer availability)
 - VACNT height: 20 μm to 200 μm (may not be able to specify, best effort)
 - VACNT coverage: blanket or specified area
 - VACNT growth may adversely affect through hole edges

Kristan Corwin, Chief
Applied Physics Division

Steven J. Choquette, Director
Office of Reference Materials
Material Measurement Laboratory

Gaithersburg, MD 20899
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Standard Configurations:

- 6006a** Micro-machined silicon aperture, 8-12 μm thick aperture, no metal coating
- 6006b** Micro-machined silicon aperture, 8-12 μm thick aperture, metal coating on aperture/front side
- 6006e** Micro-machined silicon aperture, 200-1000 nm thick aperture, no metal coating
- 6006f** Micro-machined silicon aperture, 200-1000 nm thick aperture, metal coating on aperture/front side
- 6006g** Micro-machined silicon aperture, 300-500 μm thick through holes, vertically-aligned carbon nanotubes on one side

All Si dimensions and thicknesses are best effort basis and not guaranteed. Additionally, coating performance (e.g. reflectance, metal thickness, nanotube height) is best effort basis and not guaranteed.

Apertures are fabricated on a 76.2 mm (3 inch) diameter wafer. If space allows, multiple copies of the aperture chip will be fabricated on one wafer.

The critical feature of the precision micro-machined apertures is the aperture width. The width will be inspected with an optical microscope, which has been calibrated against a NIST-traceable stage micrometer.

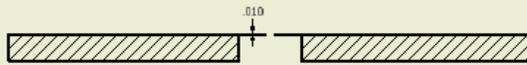
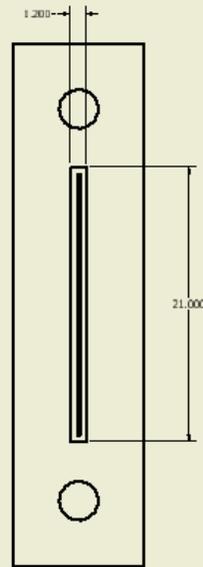
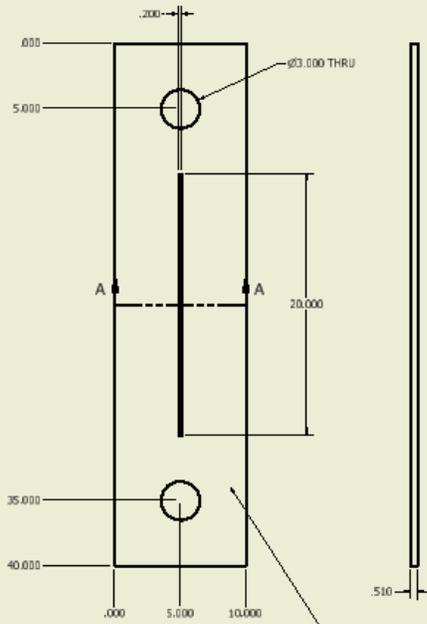
Customers will receive a detailed fabrication and calibration report along with the SRI.

Delivery and Shipping: NIST will prepare packaging for shipment of the SRI. Shipping costs will be included in each quote. Customers are responsible for all customs duties and import fees (HTC 9002.90.9500).

(sample drawing for option 6006b)

front side

back side

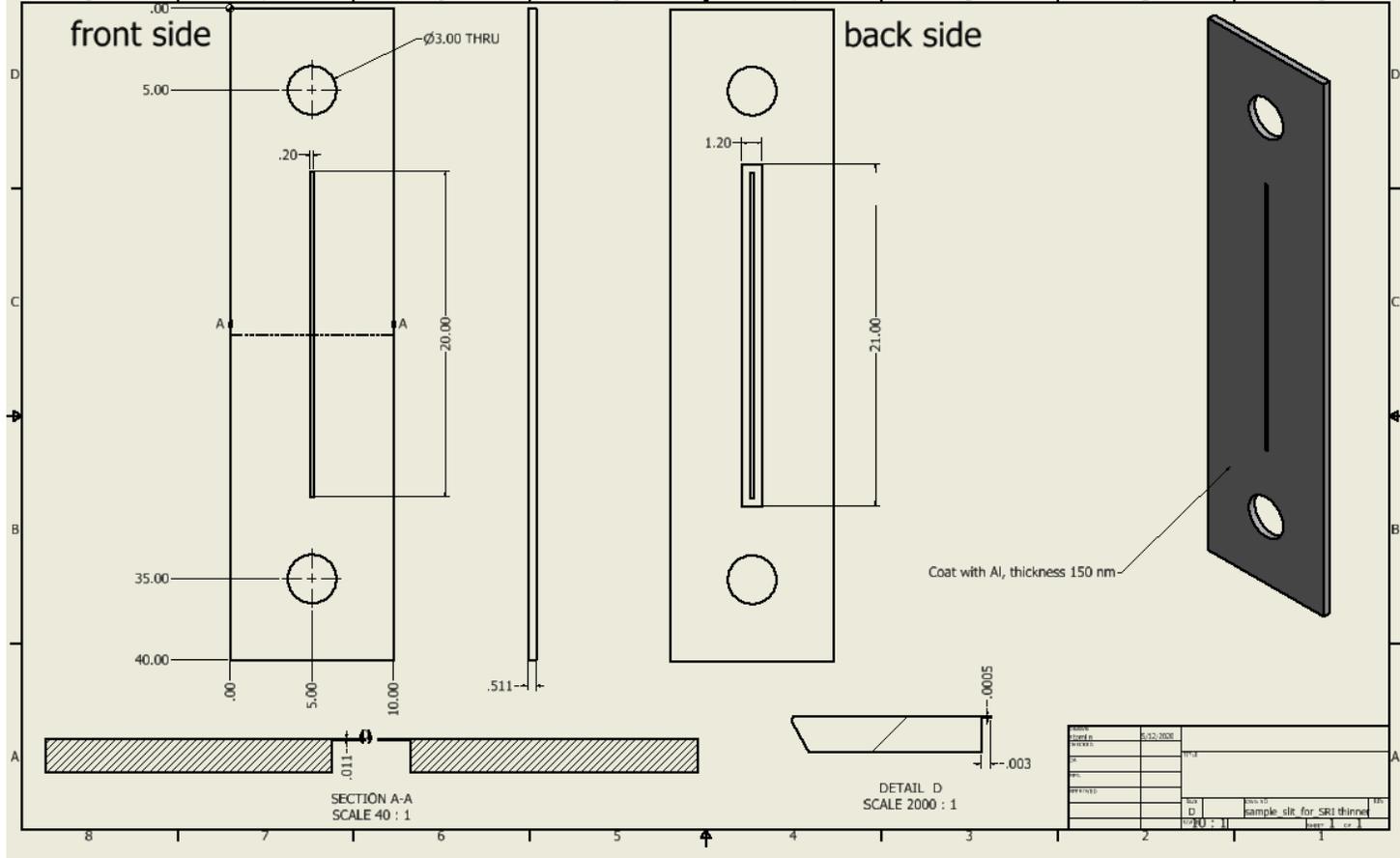


SECTION A-A
SCALE 20 : 1

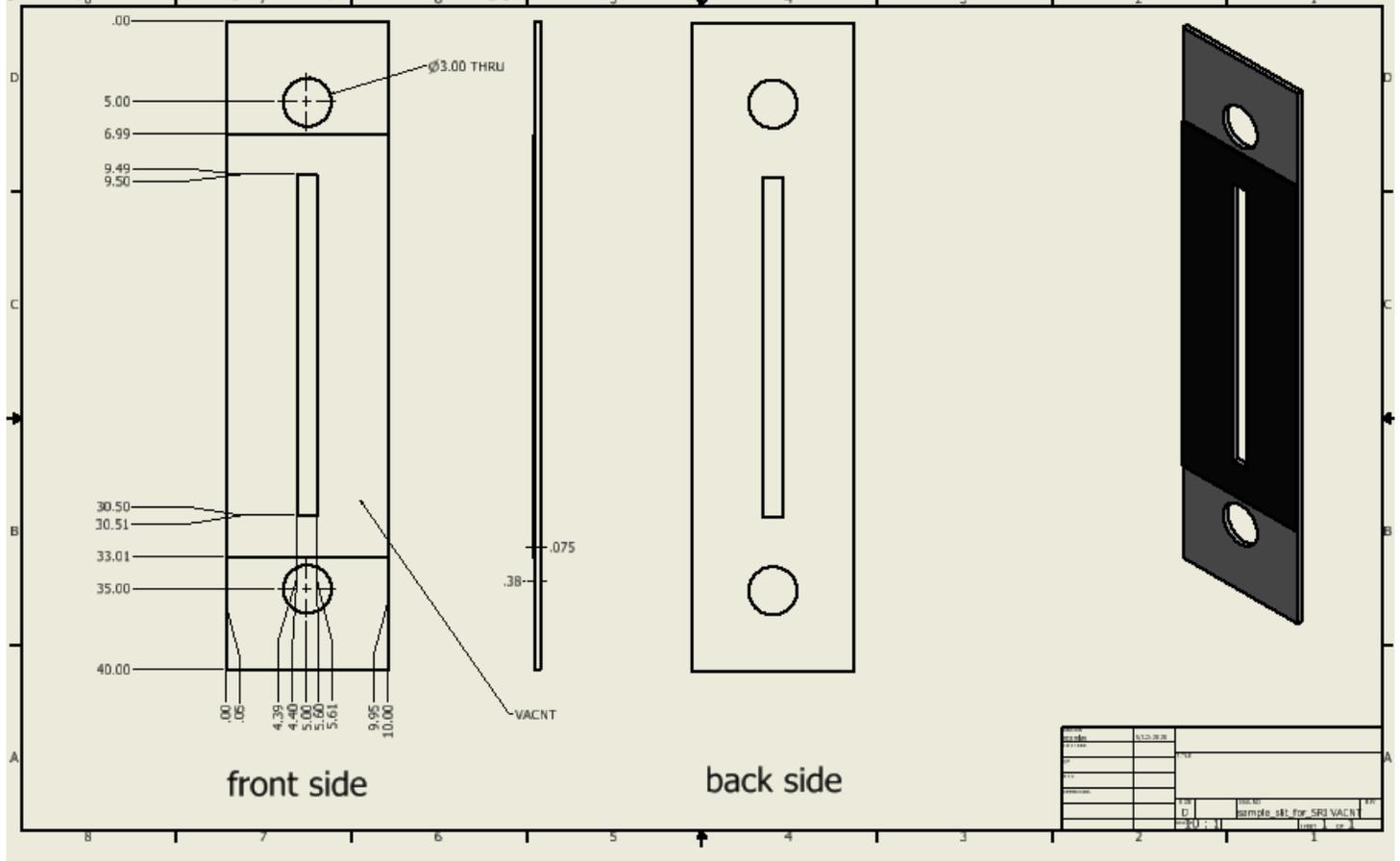
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SHEET 1 OF 1

(sample drawing for option 6006f)



(sample drawing for option 6006g)



Users of this SRI should ensure that the Specifications Certificate in their possession is current. This can be accomplished by contacting the Office of Reference Materials: telephone (301) 975-2200; fax (301) 948-3730; e-mail srminfo@nist.gov; or via the Internet at <http://www.nist.gov/sri>.